



566.41259X00

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): UCHIDA, et al.  
Serial No. 10/069,404  
Filed: May 26, 2002  
For: POLISHING MEDIUM FOR CHEMICAL-MECHANICAL  
POLISHING, AND POLISHING METHOD  
Group: 1765  
Examiner: L. Eronini

**AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

March 22, 2005

Sir:

In response to the Office Action mailed September 22, 2004, please amend the above-identified application as listed in the following, and as set forth on the following pages:

**Amendments to the Claims; and**

**Remarks** are included following the amendments.

03/24/2005 JADD01 00000062 10069404